

Resource Summary Report

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Rigaku: WaferX 310 spectrometer

RRID:SCR_020487

Type: Tool

Proper Citation

Rigaku: WaferX 310 spectrometer (RRID:SCR_020487)

Resource Information

URL: <https://www.rigaku.com/products/semi/waferx310>

Proper Citation: Rigaku: WaferX 310 spectrometer (RRID:SCR_020487)

Description: In line, simultaneous WDXRF spectrometer film thickness and composition measurements on blanket wafers.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: WaferX 310 spectrometer

Resource ID: SCR_020487

Alternate IDs: Model_Number_WaferX 310

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260903T235655+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: WaferX 310 spectrometer.

No alerts have been found for Rigaku: WaferX 310 spectrometer.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.